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EE C247B - ME C218 Introduction to MEMS Design Spring 2020

Prof. Clark T.-C. Nguyen

Dept. of Electrical Engineering & Computer Sciences
University of California at Berkeley
Berkeley, CA 94720

Lecture Module 7: Mechanics of Materials

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Outline

- Reading: Senturia, Chpt. 8
- Lecture Topics:
 - ↗ Stress, strain, etc., for isotropic materials
 - ↗ Thin films: thermal stress, residual stress, and stress gradients
 - ↗ Internal dissipation
 - ↗ MEMS material properties and performance metrics

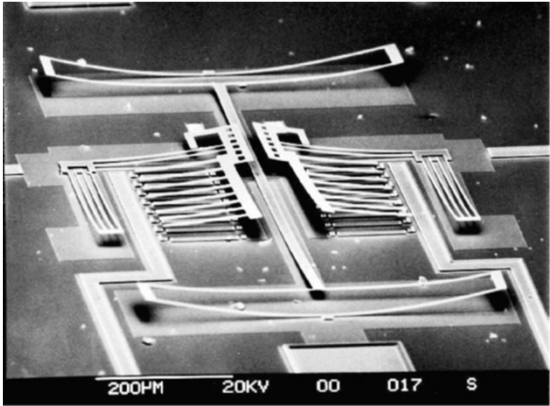
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Vertical Stress Gradients

- Variation of residual stress in the direction of film growth
- Can warp released structures in z-direction



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Elasticity

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Normal Stress (1D)

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If the force acts normal to a surface, then the stress is called a **normal stress**

Force assumed uniform over the whole area A

Stress = $\left\{ \begin{array}{l} \text{Force per} \\ \text{unit area} \end{array} \right\} = \sigma = \frac{F}{A}$ [N/m² = Pa]
 standard mks unit

⇒ **Microscopic Definition**: force per unit area acting on the surface of a differential volume element of a solid body

⇒ **Note**: assume stress acts uniformly across the entire surface of the element, not at just a point

Differential volume element

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Strain (1D)

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Sometimes a unit called the "microstrain" is used, where $\mu\epsilon = 10^{-6}$
 $1 \mu\epsilon = \frac{\Delta L}{L}$ of 1 part in 10⁶

Strain = $\left\{ \begin{array}{l} \text{Fractional Change} \\ \text{in length} \end{array} \right\} = \epsilon = \frac{L' - L}{L} = \frac{\Delta L}{L}$ [unitless]

In the elastic regime (i.e., for "small" stresses at "low" temperatures), strain is found to be proportional to stress

σ ← Stress For solids: MPa → GPa σ = εE → $\epsilon = \frac{\sigma}{E}$ [unitless]

linear regime slope = E = Young's modulus of elasticity ε ← strain

Thus, the units of E are the same as σ → Pa

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The Poisson Ratio

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Apply normal stress to a free-standing object

- uniaxial strain
- but also get contraction in directions transverse to the uniaxial strain

⇒ contraction creates a (-) strain:

$$\epsilon_y = \frac{W' - W}{W} = \frac{\Delta W}{W} = -\nu \epsilon_x$$

ν = Poisson ratio [unitless]

↳ typical values: 0 → 0.5

- ⇒ inorganic solids: 0.2 → 0.3
- ⇒ elastomers (e.g., rubber): ~ 0.5

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Shear Stress & Strain (1D)

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Note: Assume compensating forces are applied to the vertical faces to avoid a net torque. (This by convention.)

Shear Stress = $\left\{ \begin{array}{l} \text{Force per Unit Area} \\ \text{Parallel to the Surfaces} \end{array} \right\} = \tau = \frac{F}{A}$ [Pa]

Generates a shear strain:

Shear Strain = $\theta = \frac{\tau}{G}$ G ≙ shear modulus

$$G = \frac{E}{2(1 + \nu)}$$

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2D and 3D Considerations

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- Important assumption:** the differential volume element is in static equilibrium \rightarrow no net forces or torques (i.e., rotational movements)
 - Every σ must have an equal σ in the opposite direction on the other side of the element
 - For no net torque, the shear forces on different faces must also be matched as follows:

Stresses acting on a differential volume element

$$\tau_{xy} = \tau_{yx} \quad \tau_{xz} = \tau_{zx} \quad \tau_{yz} = \tau_{zy}$$

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2D Strain

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- In general, motion consists of
 - rigid-body displacement (motion of the center of mass)
 - rigid-body rotation (rotation about the center of mass)
 - Deformation relative to displacement and rotation

- Must work with displacement vectors
- Differential definition of axial strain: $\epsilon_x = \frac{u_x(x + \Delta x) - u_x(x)}{\Delta x} = \frac{\partial u_x}{\partial x}$

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2D Shear Strain

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\Rightarrow For shear strains, must remove any rigid body rotation that accompanies the deformation

\hookrightarrow use a symmetric definition of shear strain:

$$\tau_{xy} = \theta_2 + \theta_1 \approx \left(\frac{\Delta u_x}{\Delta y} + \frac{\Delta u_y}{\Delta x} \right) = \left(\frac{\partial u_x}{\partial y} + \frac{\partial u_y}{\partial x} \right)$$

For small amplitude deformations.

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Isotropic Elasticity in 3D

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- Isotropic = same in all directions
- The complete stress-strain relations for an isotropic elastic solid in 3D: (i.e., a generalized Hooke's Law)

$$\epsilon_x = \frac{1}{E} [\sigma_x - \nu(\sigma_y + \sigma_z)] \quad \gamma_{xy} = \frac{1}{G} \tau_{xy}$$

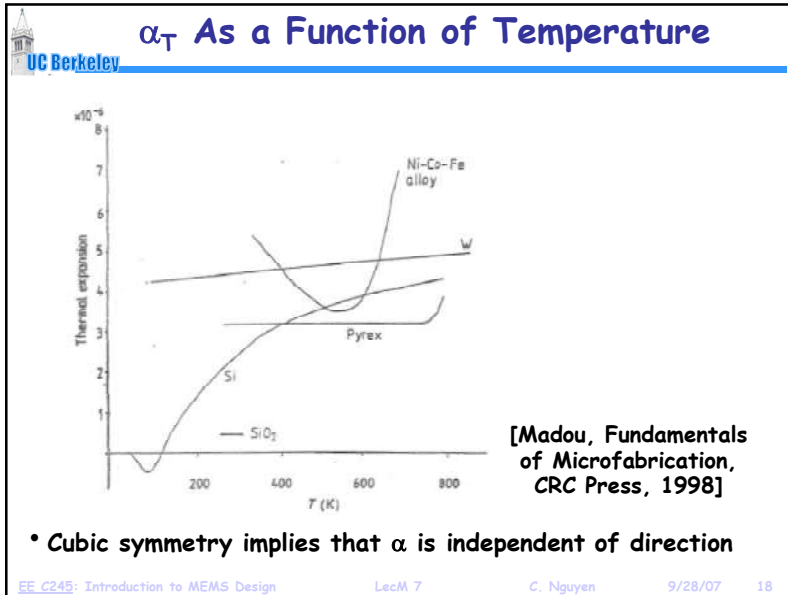
$$\epsilon_y = \frac{1}{E} [\sigma_y - \nu(\sigma_z + \sigma_x)] \quad \gamma_{yz} = \frac{1}{G} \tau_{yz}$$

$$\epsilon_z = \frac{1}{E} [\sigma_z - \nu(\sigma_x + \sigma_y)] \quad \gamma_{zx} = \frac{1}{G} \tau_{zx}$$

Basically, add in off-axis strains from normal stresses in other directions

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